

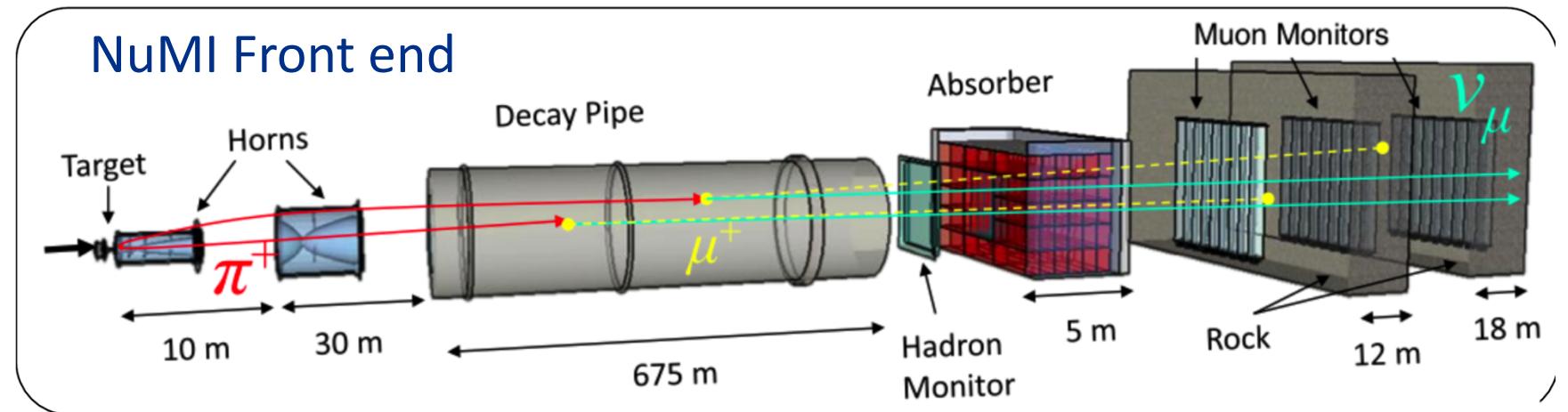


Progress of Gas-Filled Multi-RF-Cavity Beam Profile Monitor for Intense Neutrino Beams

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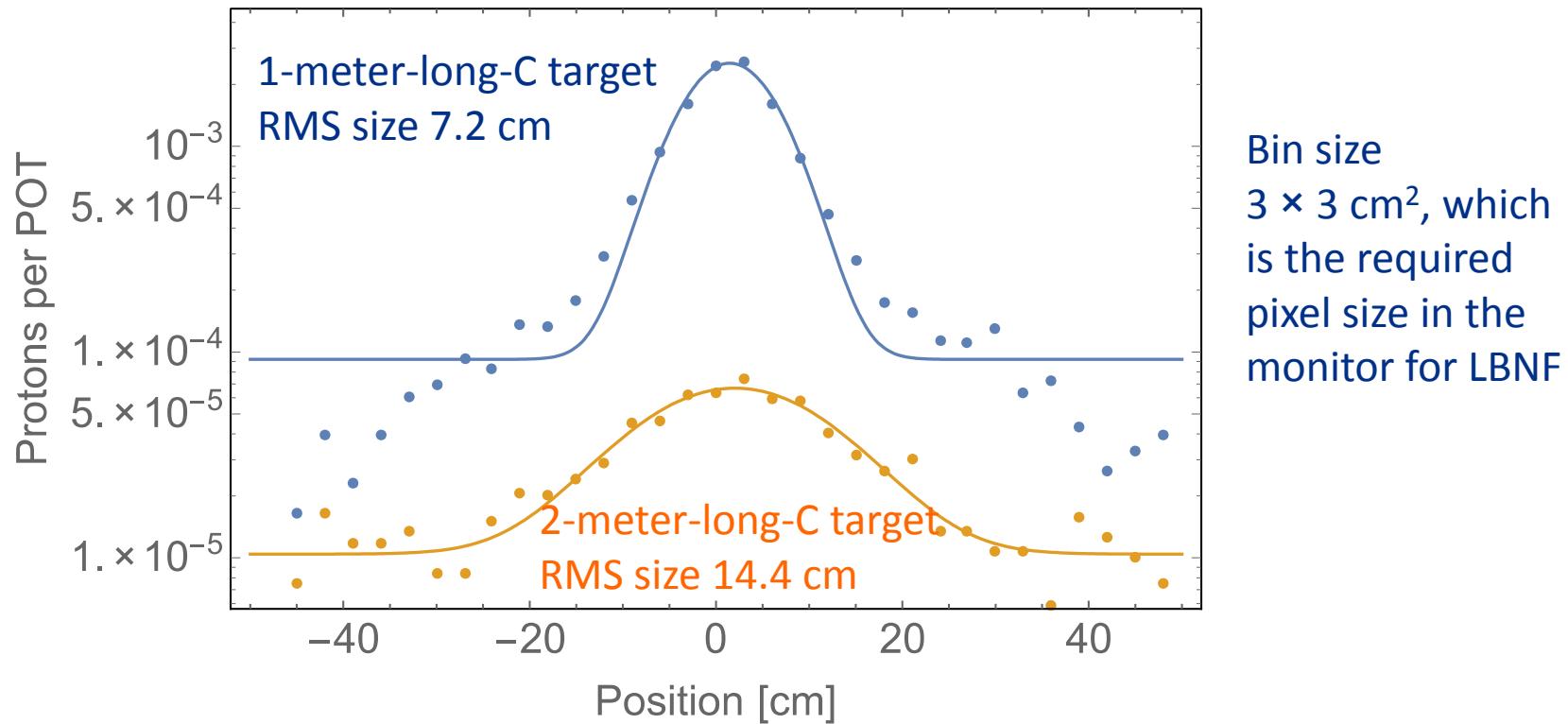
Beam Profile Monitor in Neutrino Beam Line



- Beam profile monitor in a front end of a neutrino beam
 - Combination of hadron and muon monitors
 - Monitor beam centroid
- Hadron monitor is exposed to severe radiation[1]
 - It locates at the end of a decay pipe without shielding
 - Radiation hardness is a potential issue for multi-MW beam

Simulated Secondary Beam Profile in LBNF

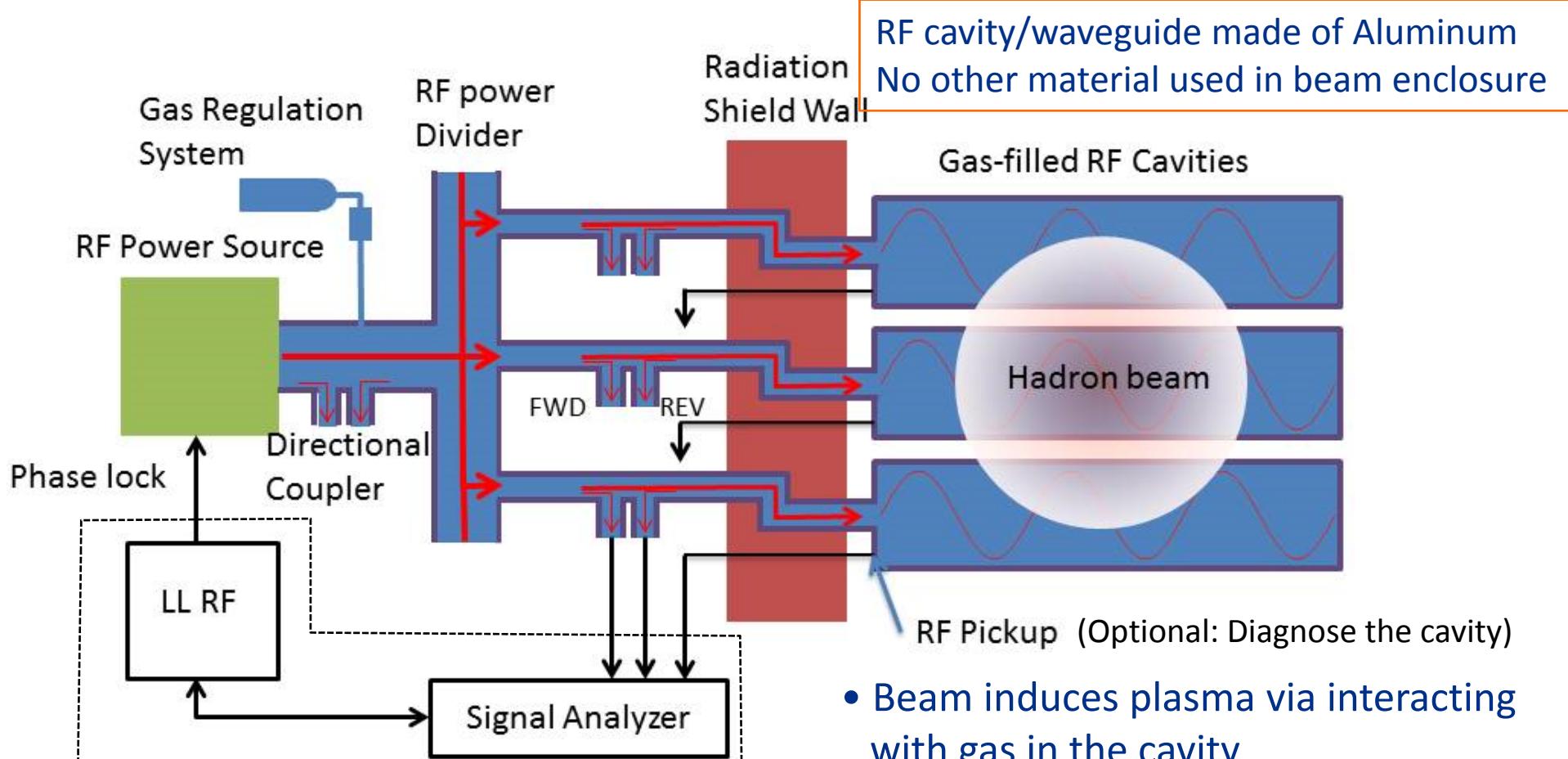
Fraction of secondary protons per single proton on target
at the end of a 200-m decay pipe (by using G4Beamline[2])



Primary proton beam for LBNF (Long Baseline Neutrino Facility)

- 120 GeV protons; 1.5E14 ppp for 2.4 MW; 20 ns bunch gap
- 10 μsec pulse length; 1.2 s cycle time
- Highest secondary proton intensity $5\text{E}10 \text{ ppp/cm}^2$ in this bin size

Possible Radiation Hard RF Gas Monitor



RF cavity/waveguide made of Aluminum
No other material used in beam enclosure

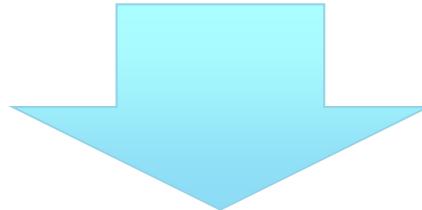
- Beam induces plasma via interacting with gas in the cavity
- Plasma changes gas permittivity
- Permittivity change is measured by observing frequency shift and Q factor change

Concept of RF Gas Monitor

- Gas permittivity is sensed by a microwave-resonant cavity
 - Permittivity change modulates the resonant frequency and the quality factor
- Permittivity change is proportional to the number of ion pairs in the RF cavity
 - Measure the number of ion pairs to reconstruct the number of incident charged particles in the cavity
- Degree of permittivity change is dependent on the species of plasma particles
 - Electrons contribute the most for RF modulations because of their light mass
 - Control the plasma population in cavities is essential
 - The change is also influenced by the RF amplitude and gas pressure

R&D of RF Gas Monitor

- Verify the concept of RF gas monitor in experiment
- Study plasma dynamics in the range of RF gas monitor
 - RF amplitude: Available lowest amplitude – 0.1 MV/m
 - Gas pressure: Available lowest pressure – 10 atm
 - Gas species: N₂, He, H₂, O₂, Dry Air, CO₂, etc
 - High RF frequencies: 2.45 GHz, 9.6 GHz
- Demonstrate feasibility of the system



Propose beam test

Plasma Population

Simplified time domain rate equation

$$\frac{dn_e}{dt} = \dot{n} - \beta n_e n_+ - \frac{n_e}{\tau},$$

$$\frac{dn_+}{dt} = \dot{n} - \beta n_e n_+ - \eta n_+ n_-,$$

$$\frac{dn_-}{dt} = \frac{n_e}{\tau} - \eta n_+ n_-$$

No dissociation
No distinguish of ion cluster
nor ion polymer

Need β , τ , η to complete
the rate equation

Ion pair production rate has
been studied and tested its
validation in experiment

\dot{n} : Ion pair production rate [cm⁻³ s⁻¹]

n_e : Number density of electrons [cm⁻³]

n_+ : Number density of positive ions [cm⁻³]

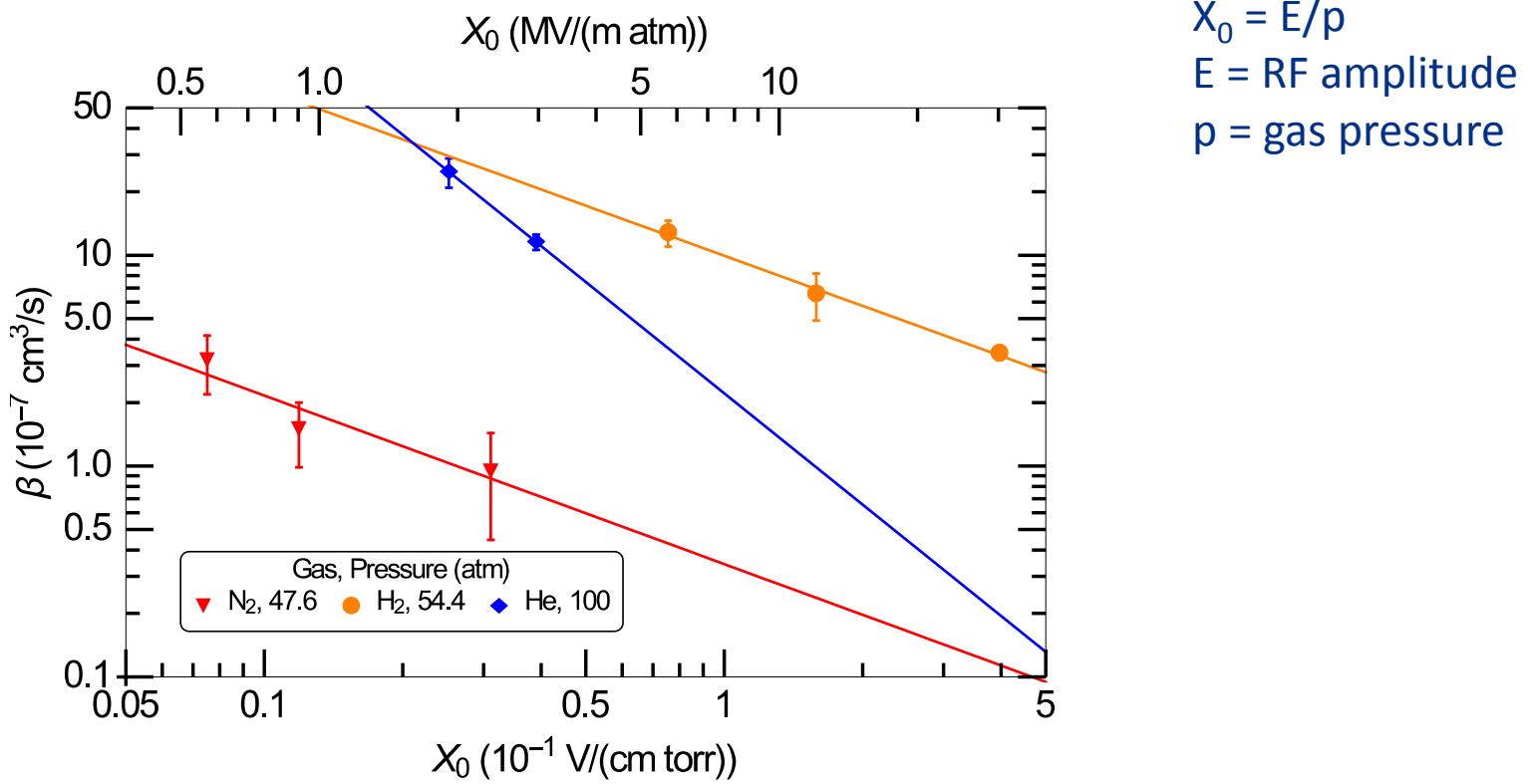
n_- : Number density of negative ions [cm⁻³]

β : Effective electron-ion recombination rate [cm³/s]

τ : Effective electron capture time [s]

η : Effective ion-ion recombination rate [cm³/s]

Effective Electron-Ion Recombination[3]

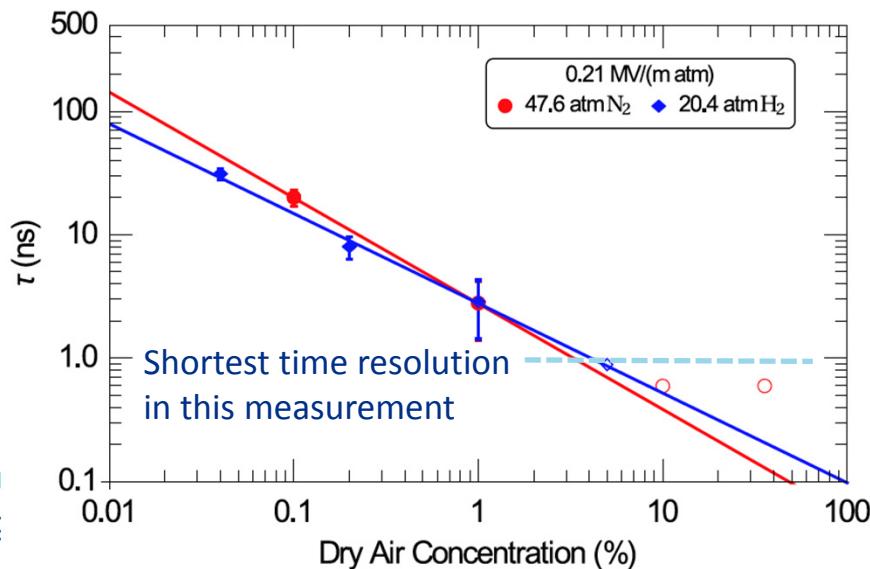


Electron-Ion recombination time = (Positive ion density $\times \beta^{-1}$)
 $\approx (10^{13} \times 10^{-7})^{-1} = 10^{-6} \text{ sec} < \text{Beam pulse length @ LBNF (10 } \mu\text{s)}$

Great amount of ion pairs disappear at the end of beam pulse!!
It induces a systematic uncertainty to reproduce plasma population

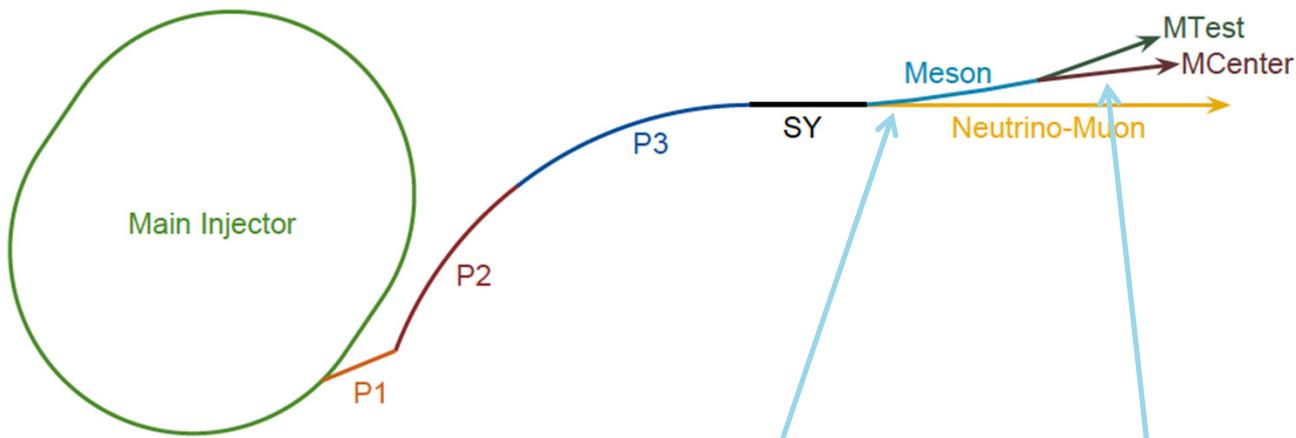
Remove Electrons by Electronegative[3]

- Doping electronegative in gas to remove electrons
 - Produce positive-negative ion pairs instead of electron-ion one
 - Ion-ion recombination time is order of magnitude longer than electron-ion recombination time
 - Contribution of electrons is negligible when $\tau \leq$ a half RF period
 - $\tau \leq 1$ ns is probably acceptable to have a practical system
- Plasma loading is ~ 100 times less with dopant
 - Save stored RF energy from RF power consumption by plasma



Require τ measurement in the range of RF gas monitor

Possible Beam Test at Fermilab



	SY dump[4]	M01
Proton energy	120 GeV	120 GeV
Beam pulse length	10 μ sec (fast kicker)	4 sec (slow ext.)
Integrated beam intensity per pulse	1E13	4E12
Availability	Limited	Unlimited
Purpose	Close to NuMI/LBNF beam profile: Verify the concept: Study plasma physics	Pretest the RF test equipment including with gas filled cavities and RF sources

Summary

- Propose a novel pressurized gas-filled multi-RF-cavity beam profile monitor that is robust in high-radiation environments
 - Useful for intense neutrino beam line, e.g. NuMI and LBNF
- R&D of the RF gas monitor in experiment
 - Control the plasma population in cavities is essential
 - Doping electronegative removes electrons in cavities within 1 nsec or shorter than a half RF period
- Consider possible beam test facility
 - M01 and SY dump are a good candidate

Citations

- [1] R. Zwaska, “NuMI Hadron Monitor”, http://docs.dunescience.org/cgi-bin/RetrieveFile?docid=1403&filename=zwaska_hadmon_final_v1_shortened.pdf&version=1
- [2] G4Beamline, <http://www.muonsinternal.com/muons3/G4beamline>
- [3] B. Freemire, “Pressurized rf Cavities in Ionizing Beams”, PRAB **19**, 062004, 2016,
- [4] A. Watts, “Magnetic Control of Fermilab Switchyard Beam Splits”, <http://beamdocs.fnal.gov/AD/DocDB/0050/005040/002/magnetic-control-fermilab%20%281%29.pdf>

Q. Liu, “Future Prospects of RF Hadron Beam Profile Monitors for Intense Neutrino Beam”, TUPOA44

- Discuss about temperature increment of RF cavities and possible cavity shapes